

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Ji-soo KIM et al.

Serial No.: [NEW]

Attn: Applications Branch

Filed: 30 September 2003

For: METHOD OF DETERMINING DEGREE OF CHARGE-UP INDUCED BY
PLASMA USED FOR MANUFACTURING SEMICONDUCTOR DEVICE AND
APPARATUS THEREFOR

CLAIM OF PRIORITY

U.S. Patent and Trademark Office
2011 South Clark Place
Customer Window, **Mail Stop Patent Application**
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Sir:

Applicants, in the above-identified application, hereby claim the priority date
under the International Convention of the following Korean application:

Appln. No. 1999-33858 filed August 17, 1999

as acknowledged in the Declaration of the subject application.

A certified copy of said application was submitted in the parent application.

Respectfully submitted,

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Dated: 30 September 2003

대한민국 특허청
KOREAN INDUSTRIAL
PROPERTY OFFICE

별첨 사본은 아래 출원의 원본과 동일함을 증명함.

This is to certify that the following application annexed hereto
is a true copy from the records of the Korean Industrial
Property Office.

출원 번호 : 1999년 특허출원 제33858호
Application Number

출원 년 월 일 : 1999년 8월 17일
Date of Application

출원 인 : 삼성전자 주식회사
Applicant(s)

1999년 11월 18일

특 허 청
COMMISSIONER

